

REMARKS

The Applicant thanks the Examiner for the careful examination of this application and respectfully requests the entry of the amendments indicated hereinabove.

Claims 13 and 17 are pending and rejected. Claim 13 is canceled and Claim 17 is amended hereinabove. More specifically, Claim 17 was amended in response to the 35 U.S.C. §112, second paragraph rejection.

Amended Claim 17 positively recites providing a plurality of effusion cells, each effusion cell having a plurality of ports, the ports of each effusion cell offset from the ports of the other effusion cells. Amended Claim 17 also positively recites transporting a substrate across the plurality of effusion cells and continuously effusing an emissive material from the ports in each effusion cell to form a plurality of emissive strips. These advantageously claimed features are not taught or suggested by WO99/20080, or the patents granted to Himeshima et al., or Namiki et al.; either alone or in combination.

Himeshima et al. teaches the formation of an emitting layer by resistance heating evaporation, electron beam evaporation, or sputtering evaporation (column 7 line 66 through column 8 line 2). In addition, Himeshima et al. teaches that the

preferred method of forming the emitting layer is resistance evaporation and electron beam evaporation (column 8 lines 2-4, see also column 10 lines 11-17 and 27-33). Therefore, Himeshima et al. does not teach providing a plurality of effusion cells, or continuously effusing an emissive material from the ports in each effusion cell to from a plurality of emissive strips, as advantageously claimed.

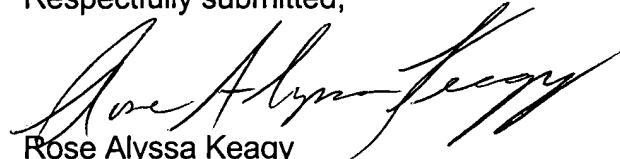
The Applicant submits that WO99/20080 does not teach or suggest the advantageously claimed invention for the reasons listed above concerning the Himeshima et al. patent.

Namiki et al. teaches the formation of an emitting layer by lamination (column 5 line 65, column 6 lines 61-62). Therefore, Namiki et al. does not teach providing a plurality of effusion cells, or continuously effusing an emissive material from the ports in each effusion cell to from a plurality of emissive strips, as advantageously claimed.

Therefore, the Applicants respectfully traverse the Examiner's rejection of Claim 17 and respectfully assert that Claim 17 is patentable over WO99/20080, and the patents granted to Himeshima et al., and Namiki et al.; either alone or in combination

For the reasons stated above, this application is believed to be in condition for allowance. Reexamination and reconsideration is requested.

Respectfully submitted,



Rose Alyssa Keagy
Attorney for Applicant
Reg. No. 35,095

Texas Instruments Incorporated
PO BOX 655474, M/S 3999
Dallas, TX 75265
972/917-4167
FAX - 972/917-4409/4418